METHOD FOR MANUFACTURING OF PELLICLE

ABSTRACT OF THE DISCLOSURE.

A method for manufacturing of a pellicle that can simplify the manufacturing process is provided.

The method for manufacturing of a pellicle comprises a step for forming a SiC film on a bottom surface of a Si substrate, a step for bonding a supporting member including a through hole to a bottom surface of the SiC film, and a step for removing the Si substrate, after bonding the supporting member.

[Fig. 6]